



Attorney's Docket No.: 005794 ALRT/ETCH/CONE/  
Confirmation No.: 3777

Patent

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In Re Application of:

Mark N. Kawaguchi, et al.

Application No.: 09/978,121

Filed: October 15, 2001

For: A METHOD OF PHOTORESIST  
REMOVAL IN THE PRESENCE  
OF A DIELECTRIC LAYER  
HAVING A LOW K-VALUE

Examiner: Olsen, Allan W.

Art Unit: 1763

Mail Stop: RCE  
Commissioner for Patents  
P. O. Box 1450  
Alexandria, VA 22313-1450

AMENDMENT AND RESPONSE TO OFFICE ACTION

Dear Sir:

In response to the Office Action dated December 7, 2004, Applicant respectfully requests that the above-identified application be amended as follows and that the following remarks be considered:

FIRST-CLASS CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as first-class mail with sufficient postage in an envelope addressed to Mail Stop: Amendment, Commissioner for Patents, P. O. Box 1450, Alexandria, VA 22313-1450, on:

April 7, 2005

Date of Deposit

Esther Campbell

Name of Person Mailing Correspondence

*Esther Campbell*

Signature

April 7, 2005

Date

Inventor(s): Mark N. Kawaguchi, et al.  
Application No.: 09/978,121

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